


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: MARAKHTANOV et al Serial No.: 10/808,795 Filed: March 24, 2004 Title: PLASMA PROCESSING SYSTEM CONTROL		Group Art Unit: 2821-2828 Examiner: UNASSIGEND Docket: P1220/LMRX-P030 Confirmation No.: 6020
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INFORMATION DISCLOSURE STATEMENT

US PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant	Reference to Related Case
D		US-5933314	1999-08-03	Lambson et al.	

FOREIGN PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number	Publication Date	Applicant	Reference to Related Case	T

OTHER DOCUMENTS

Examiner Initials	Cite No.		T
D	/	Kawamura et al., "Ion energy distributions in RF sheaths; review, analysis and simulation", 1999, Plasma Sources Science Technology 8, R45-R64.	
		Lieberman et al., "Principles of Plasma Discharges and Materials Processing", 1994, New York, John Wiley and Sons, Inc..	

Examiner Signature	David Vn	Date Considered	6/12/05
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